

On December 5, 2005 at the Plenary session of the IEEE EDS International Electron Devices Meeting (IEDM) in Washington, D.C., the 2005 EDS President, Hiroshi Iwai, presented a number of 2005 IEEE/EDS Fellows with certificates to congratulate them on being elected IEEE Fellows. Fourteen of the 40 EDS members elected to the IEEE grade of Fellow for 2005 attended the presentation.

### 40 EDS Members Elected to the IEEE Grade of Fellow Effective 1 January 2005

# Supriyo Bandyopadhyay, Virginia Comonwealth Univ., Richmond, VA, USA

for contributions to device applications of nanostructures

# Henri Marius Baudrand, Ecole Nationale Supérieure d'Electrotechnique, Toulouse, France

for contributions to the electromagnetic modeling of microwave circuits and antennas

Robert Christopher Baumann, Texas Instruments, Dallas, Texas, USA for contributions to the understanding of the reliability impact of terrestrial radiation mechanisms in commercial electronics

### Duane S. Boning, MIT, Cambridge, MA, USA

for contributions to modeling and control in semiconductor manufacturing

# William D. Brown, University of Arkansas, Fayetteville, AR, USA for leadership in furthering education of high density electronics

Jeff D. Bude, Agere Systems, New Providence, NJ, USAfor contributions to the deep submicron MOSFETs

#### Robert S. Chau, Intel Corporation, Beaverton, OR, USA

for contributions to gate dielectric and transistor technology for microprocessors

## Clifton G. Fonstad, Massachusetts Inst. of Technology, Cambridge, MA, USA

for leadership in compound semiconductor heterostructure devices

# William Robert Frensley, University of Texas at Dallas, Richardson, TX, USA

for contributions to nanometer-scale quantum semiconductor devices

### Guido V. Groeseneken, IMEC, Leuven, Belgium

for his contributions to the physical understanding and the modeling of reliability of metal oxide semiconductor field effect transistors

#### Ken-ya Hashimoto, Chiba University, Chiba, Japan

for contributions to simulation and design for surface acoustic wave devices

### George L Heiter, Heiter Microwave Consulting, Westford, MA, USA

for contributions to microwave circuits, including linear amplifiers and space diversity combiners

## G. Benjamin Hocker, Honeywell Laboratories (Retired), Minnetonka, MN, USA

for leadership in microelectromechanical system technology

# James Albert Hutchby, Semiconductor Research Corp., Triangle Park, NC, USA

for contributions to the design of low power static random access memories

## Tadao Ishibashi, NTT Electronics Corporation, Kanagawa, Japan

for contributions to high-speed and optoelectronic semiconductor devices

Noble M. Johnson, Palo Alto Research Cneter, Palo Alto, CA, USA for contributions to the control of impurities in semiconductors

Masaaki Kuzuhara, NEC Corporation, Otsu, Shiga Prefecture, Japan for contributions to Group III-V microwave power devices

Joy Laskar, Georgia Institute of Technology, Atlanta, GA, USA for contributions to the modeling and development of high frequency communication modules

Kartikeya Mayaram, Oregon State Univ, Corvallis, OR, USA for contributions to coupled device and circuit simulation

# Deirdre R. Meldrum, University of Washington, Seattle, Washington, USA

for contributions to genome automation

John Melngailis, University of Maryland, College Park, MD, USA for contributions to focused ion beam applications

Hisayo Sasaki Momose, Toshiba Corporation, Kanagawa, Japan for contributions to ultra-thin gate oxide metal oxide semiconductor fields effect transistors

Mehrdad M. Moslehi, Semizone Inc., Palo Alto, CA, USA for contributions to single wafer processing technologies

Laurence W. Nagel, Omega Enterprises, Randolph, NJ, USA for contributions to the field of integrated circuit simulation

# Hidehito Obayashi, Hitachi High-Technologies Corporation, Ibaraki, Japan

for contributions to critical dimension scanning electron microscopy

### Yutaka Ohmori, Osaka University, Osaka, Japan

for contributions to the development of organic and semiconductor light emitting materials and devices

# Shinji Okazaki, Assoc. of Super-Advanced Elec. Technologies, Tokyo, Japan

for contributions to the resolution enhancement technology in optical and electron-beam lithography

#### Manijeh Razeghi, Northwestern University, Evanston, IL, USA

for contributions to the development of compund semiconductor growth technology

### Mark Stephen Rodder, Texas Instruments, Dallas, TX, USA

for contributions to deep sub-micron complementary metal oxide semiconductor technology

#### Enrico James Sangiorgi, University of Bologna, Cesna, Italy

for contributions to the modeling and characterization of hot carriers and non stationary transport effects in small silicon devices

### Phillip Miles Smith, BAE Sytems, Nashua, NH, USA

for contributions to microwave high electron mobility transistors

#### Tangali S. Sudarshan, Univ. of South Carolina, Columbia, SC, USA

for contributions to surface flashover of dielectric and semiconductor materials

#### Hidehiko Tanaka, University of Tokyo, Tokyo, Japan

for contributions tohigh performance computation models

## Juzer M. Vasi, Indian Institute of Technology (IIT) Bombay, Mumbai, India

for leadership in microelectronics education

# Sophie V. Verdonckt-Vandebroek, Xerox Corporation, Webster, NY, USA

for leadership in developing photocopier products

#### Lois D. Walsh, Air Force Research Lab, Rome, NY, USA

for leadership in electronic device reliability

#### Kevin John Webb, Purdue University, West Lafavette, IN, USA

for contributions to numerical modeling and characterization techniques of passive and active devices

#### Jason Chik-Shun Woo, UCLA, Los Angeles, CA, USA

for contributions to nanoscale sillicon on insulator and bulk metal oxide semiconductor device physics and technology

# Donald Coolidge Wunsch, University of Missouri - Rolla, Rolla, MO, USA

for contributions to hardware implementations of reinforcement and unsupervised learning

Kazuo Yano, Central Research Laboratory, Hitachi, Ltd., Tokyo, Japan for contributions to nanostructured-silicon devices and circuits and advanced CMOS logic